



(51) International Patent Classification:

B81C 1/00 (2006.01) *B81B 7/02* (2006.01)
B81B 7/00 (2006.01) *H01L 27/04* (2006.01)

(21) International Application Number:

PCT/US2016/012133

(22) International Filing Date:

5 January 2016 (05.01.2016)

(25) Filing Language:

English

(26) Publication Language:

English

(30) Priority Data:

14/687,943 16 April 2015 (16.04.2015) US

(71) Applicant: **THE GOVERNMENT OF THE UNITED STATES OF AMERICA, AS REPRESENTED BY THE SECRETARY OF THE NAVY** [US/US]; 875 North Randolph Street, Suite 1425, Arlington, VA 22203 (US).

(72) Inventors; and

(71) Applicants : **MEYER, David, J.** [US/US]; 10401 Darby Street, Fairfax, VA 22030 (US). **DOWNEY, Brian, P.** [—/US]; 6367 Chimney Wood Ct, Alexandria, VA 22306 (US).

(74) Agent: **BROOME, Kerry, L.**; US Naval Research Laboratory, 4555 Overlook Ave, SW, Code 1008.2, Washington, DC 20375 (US).

(81) Designated States (unless otherwise indicated, for every kind of national protection available):

AE, AG, AL, AM, AO, AT, AU, AZ, BA, BB, BG, BH, BN, BR, BW, BY, BZ, CA, CH, CL, CN, CO, CR, CU, CZ, DE, DK, DM, DO, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT, HN, HR, HU, ID, IL, IN, IR, IS, JP, KE, KG, KN, KP, KR, KZ, LA, LC, LK, LR, LS, LU, LY, MA, MD, ME, MG, MK, MN, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PA, PE, PG, PH, PL, PT, QA, RO, RS, RU, RW, SA, SC, SD, SE, SG, SK, SL, SM, ST, SV, SY, TH, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, ZA, ZM, ZW.

(84) Designated States (unless otherwise indicated, for every kind of regional protection available):

ARIPO (BW, GH, GM, KE, LR, LS, MW, MZ, NA, RW, SD, SL, ST, SZ, TZ, UG, ZM, ZW), Eurasian (AM, AZ, BY, KG, KZ, RU, TJ, TM), European (AL, AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HR, HU, IE, IS, IT, LT, LU, LV, MC, MK, MT, NL, NO, PL, PT, RO, RS, SE, SI, SK, SM, TR), OAPI (BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, KM, ML, MR, NE, SN, TD, TG).

Published:

— with international search report (Art. 21(3))

(54) Title: METHOD FOR FABRICATING SUSPENDED MEMS STRUCTURES

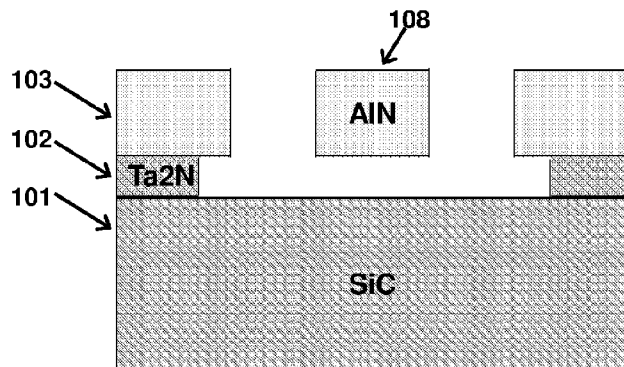


FIG. 1F

(57) Abstract: A process for fabricating a suspended microelectromechanical system (MEMS) structure comprising epitaxial semiconductor functional layers that are partially or completely suspended over a substrate. A sacrificial release layer and a functional device layer are formed on a substrate. The functional device layer is etched to form windows in the functional device layer defining an outline of a suspended MEMS device to be formed from the functional device layer. The sacrificial release layer is then etched with a selective release etchant to remove the sacrificial release layer underneath the functional layer in the area defined by the windows to form the suspended MEMS structure.



Method for Fabricating Suspended MEMS Structures

Attorney Docket No. 103151-WO1

5 This application claims the benefit of priority based on United States Patent Application No. 14/687,943 filed April 16, 2015.

TECHNICAL FIELD

10 The present invention relates to fabrication of microelectromechanical system (MEMS) structures, specifically to a new process for fabricating MEMS structures that utilizes an intermediate sacrificial release layer to form a structure having a suspended semiconductor functional layer.

BACKGROUND ART

15 The term “MEMS” is used to refer to a class of miniaturized devices, typically produced using microfabrication techniques, which contain both an electrical and a mechanical component, and have a wide variety of potential applications ranging from sensors, electronics, optics, and actuators. While MEMS are used in numerous commercial applications, device performance and capabilities can further be enhanced by the additional availability of new and higher quality materials and fabrication processes.

20 SiC and compound semiconductors, particularly Group III-Nitride (III-N) materials such as gallium nitride (GaN), aluminum nitride (AlN), indium nitride (InN), and their various alloys, have materials properties that are of great interest for MEMS applications, including high temperature stability and high electric field breakdown due to their wide band gap, excellent mechanical properties, and for III-N materials in particular, excellent piezoelectric properties. See V. Cimalla, J. Pezoldt, and O. Ambacher, “Group III nitride and SiC based MEMS and NEMS: material properties, technology and applications,”
25 Journal of Physics D: Applied Physics 40, 6386 (2007).

Both SiC and III-N materials are currently used for electronic and optoelectronic devices such as transistors for power and high frequency applications and light-emitting diodes (LEDs) and lasers, and the ability to incorporate the properties of those devices into MEMS structures is of interest.

103151-WO1

High quality single-crystal material is required for electronic and optoelectronic devices and while polycrystalline material can be used for purely mechanical devices, polycrystalline material can suffer from diminished mechanical and piezoelectric properties; therefore, a suitable release layer and growth method is required for producing
5 high quality single-crystal functional layers.

MEMS processing requires a sacrificial release layer that can be selectively removed without damaging other layers in the device structure in order to create suspended MEMS structures. While single-crystal SiC and III-N materials are commonly grown on substrates such as SiC, GaN, AlN, sapphire, and Si, there are limited methods for
10 fabricating MEMS devices using single-crystal SiC and III-N materials due to the chemical inertness of SiC and III-Ns, making these materials difficult to etch chemically.

One method that overcomes the limitations of wet etching of single-crystal SiC and III-N materials to fabricate MEMS structures is photoelectrochemical (PEC) etching. See U.S. Patent 5,374,564 to E.L. Hu and A.R. Stonas, entitled "Photoelectrochemical undercut etching of semiconductor material"; see also F. Zhao and M.M. Islam, "Fabrication of
15 single-crystal silicon carbide MEMS/NEMS for biosensing and harsh environments," 2011 IEEE 24th International Conference on Micro Electro Mechanical Systems (MEMS), 261 (2011). In PEC etching, an ultraviolet light source and suitable etchant solution are used to selectively etch a layer by oxidizing the layer surface and subsequent etching of the oxide
20 layer. The ultraviolet light illumination is required to generate holes, which is necessary for the oxidation reaction of the layer to proceed.

While PEC etching has been used previously for MEMS fabrication, there are several limitations to the method. Using wet etching to remove the sacrificial layer and release the MEMS structure has an inherent disadvantage as liquid becomes trapped
25 between the MEMS device and underlying layer as the etch proceeds. This can cause the suspended MEMS structure to be pulled into contact with the layer below where it can remain in contact, through a process known as "stiction." This effect can reduce the yield of fabricated devices. Additionally, sample rinsing and drying may cause fragile suspended structures to break, further reducing yield. Another disadvantage of this method is that the
30 MEMS structure design may be limited based on the selectivity of the etching process.

103151-WO1

Selective etching of specific layers can be performed in one of two ways, bandgap-selective etching or dopant-selective etching.

In bandgap-selective etching, the photon energy of the ultraviolet light can be selected so that holes will only be photogenerated in the lowest band gap material of the structure, which becomes the sacrificial layer. For example, a ternary InGaN layer can be used as a sacrificial release layer grown beneath a GaN layer due to the smaller band gap of the InGaN layer.

In dopant-selective etching, etch selectivity is achieved through appropriate p-type or n-type doping of the layers, where the p-type layer is the functional layer and the n-type layer is the sacrificial release layer. In the case of p-type doping, the energy bands are bent downwards so holes move away from the surface, and the oxidation process cannot proceed. In the case of n-type doping, the energy bands at the surface of the layer in the etchant solution are bent upwards, allowing photogenerated holes to participate in the oxidation process at the layer surface.

PEC etching, bandgap-selective etching, and dopant-selective etching all have several drawbacks.

For example, in bandgap-selective etching, the material with the lowest band gap will be etched, which may limit the MEMS device design if the layer with the lowest band gap in the structure is to be a functional layer and an epitaxial material with a lower band gap cannot be grown as the sacrificial layer. Similarly, in dopant-selective etching, the n-type layer must be the sacrificial layer, limiting device design.

In addition, although not always necessary, metal electrodes can be patterned on the sample to act as a cathode and to control etch rate, selectivity, and morphology. This may require extra process steps not compatible with the device process, such as additional metal depositions, metal etching, etc. Further processing following the release step may reduce MEMS device yield as the released structures are fragile and may not withstand further processing steps.

Finally, the etchants used in PEC etching, such as potassium hydroxide (KOH) and hydrochloric acid (HCl), are known to etch various metals as well as III-N materials in

103151-WO1

certain instances. For example, KOH and HCl are known to etch N-polar GaN, but not Ga-polar GaN, and KOH has been used to etch AlN and defects in GaN.

Another method used to fabricate suspended single-crystal III-N or SiC MEMS structures is via bulk micromachining where material is removed from the substrate to suspend the functional layers above.

For instance, single-crystal III-N functional layers grown on SiC can be suspended by selectively etching the SiC substrate isotropically beneath the III-N material to release the MEMS structure using a plasma-based dry etch. See F. Niebelschütz, V. Cimalla, K. Tonisch, Ch. Haupt, K. Brückner, R. Stephan, M. Hein, and O. Ambacher, “AlGaIn/GaN-based MEMS with two-dimensional electron gas for novel sensor applications,” *Physica Status Solidi C* 5 (6), 1914 (2008). However, this method requires a special hard mask to protect the functional MEMS layers, which must be removed chemically after the dry etch release step, creating additional processing steps and potentially reducing device yield since further processing is required after the release step. Additionally, the dry etch must be done at elevated temperatures in order to be isotropic, which may not be compatible with the device thermal budget. Furthermore, plasma etching may potentially cause damage to functional layers.

Other release processes that have been used to fabricate suspended single-crystal III-N MEMS structures include wet etching, see H.W. Choi, K.N. Hui, P.T. Lai, P. Chen, X.H. Zhang, S. Tripathy, J.H. Teng, and S.J. Chua, “Lasing in GaN microdisks pivoted on Si,” *Applied Physics Letters* 89, 211101 (2006); plasma etching the front side of the Si substrate, see K. Brueckner, F. Niebelschuetz, K. Tonisch, S. Michael, A. Dadgar, A. Krost, V. Cimalla, O. Ambacher, R. Stephan, and M. A. Hein, “Two-dimensional electron gas based actuation of piezoelectric AlGaIn/GaN microelectromechanical resonators,” *Applied Physics Letters* 93, 173504 (2008); dry etching vias through the backside of the Si substrate, see B.S. Kang, S. Kim, F. Ren, J.W. Johnson, R.J. Therrien, P. Rajagopal, J.C. Roberts, E.L. Piner, K.J. Linthicum, S.N.G. Chu, K. Baik, B.P. Gila, C.R. Abernathy, and S.J. Pearton, “Pressure-induced changes in the conductivity of AlGaIn/GaN high-electron mobility-transistor membranes,” *Applied Physics Letters* 85 (14), 2962 (2004); and XeF₂ etching the front side of the Si substrate, see A. Ansari and M. Rais-Zadeh, “A thickness-

103151-WO1

mode AlGaIn/GaN resonant body high electron mobility transistor,” IEEE Transactions on Electron Devices 61 (4), 1006 (2014).

These methods also have significant drawbacks.

5 There are inherent disadvantages when using the substrate as the sacrificial layer including loss of dimensional control in the vertical direction due to the nature of isotropic etching and loss of ability to have functional layers underneath the sacrificial layer, which may be required in certain device structures.

10 In addition, the choice of substrate may be limited due to availability of bulk micromachining techniques available for a given substrate. For example, III-N materials are commonly grown on sapphire, but the substrate cannot be easily etched.

15 Moreover, bulk micromachining may not be compatible for functional layers grown homoepitaxially, i.e. GaN grown on GaN substrates or SiC grown on SiC substrates, where etch selectivity between the substrate and functional layers cannot be achieved. As mentioned above, wet chemical etching release methods may decrease yield via stiction or damage from rinsing or drying. Dry etching may cause plasma damage and may require extra processing steps such as hard mask deposition and removal, which may not be compatible with device process flow and may further reduce device yield due to additional processing steps after release.

DISCLOSURE OF THE INVENTION

20 This summary is intended to introduce, in simplified form, a selection of concepts that are further described in the Detailed Description. This summary is not intended to identify key or essential features of the claimed subject matter, nor is it intended to be used as an aid in determining the scope of the claimed subject matter. Instead, it is merely presented as a brief overview of the subject matter described and claimed herein.

25 The present invention provides a process for fabricating a microelectromechanical system (MEMS) structure comprising epitaxial semiconductor functional layers that are partially or completely suspended over a substrate.

103151-WO1

In accordance with the present invention, an epitaxial sacrificial release layer is formed on the surface of a substrate and a semiconductor functional layer is formed on the surface of the release layer opposite from the substrate. In many embodiments, the substrate, the sacrificial release layer, and the functional layer are all formed from single-
5 crystal materials, while in some embodiments, one or more of the substrate, the sacrificial release layer, and the functional layer are formed from a polycrystalline or an amorphous material.

The functional device layer is etched to form one or more “windows” in the functional device layer and, in some cases in the sacrificial release layers, the windows
10 defining the outline of a suspended MEMS structure to be formed from the functional device layer. This etching step can be done using any suitable etching technique such as dry plasma, wet chemical, or ion beam etching, but in many embodiments dry etching will be preferred due to the anisotropic nature of the etch process.

The sacrificial release layer is then etched with a selective release etchant to remove
15 the sacrificial release layer underneath the functional layer in the area defined by the windows to form the suspended MEMS structure.

BRIEF DESCRIPTION OF THE DRAWINGS

FIGS. 1A-1F are block diagrams illustrating aspects of an exemplary embodiment of a method for forming a suspended MEMS structure in accordance with the present
20 invention.

FIGS. 2A-2C illustrate aspects of another exemplary embodiment of a MEMS device comprising suspended III-N layers with patterned interdigitated metal electrodes on a SiC substrate in accordance with one or more aspects of the present invention.

MODES FOR CARRYING OUT THE INVENTION

The aspects and features of the present invention summarized above can be embodied in various forms. The following description shows, by way of illustration, combinations and configurations in which the aspects and features can be put into practice.
25 It is understood that the described aspects, features, and/or embodiments are merely examples, and that one skilled in the art may utilize other aspects, features, and/or

103151-WO1

embodiments or make structural and functional modifications without departing from the scope of the present disclosure.

The present invention provides a process for fabricating a microelectromechanical system (MEMS) structure comprising epitaxial semiconductor functional layers that are partially or completely suspended over a substrate.

As described in more detail below, in accordance with the present invention, an epitaxial sacrificial release layer is formed on the surface of a substrate and a semiconductor functional layer is formed on the surface of the release layer opposite from the substrate. In many embodiments, the substrate, the sacrificial release layer, and the functional layer are all formed from single-crystal materials. In other embodiments, one or more of the substrate, the sacrificial release layer, and the functional layer can be formed from a polycrystalline material. In still other embodiments the functional layer can be formed from an amorphous material, with the substrate and sacrificial release layer being formed from a single crystal or a polycrystalline material.

The functional device layer is etched to form one or more “windows” in the functional device layer and, in some cases in the sacrificial release layers, the windows defining the outline of a suspended MEMS structure to be formed from the functional device layer. This etching step can be done using any suitable etching technique such as dry plasma, wet chemical, or ion beam etching, but in many embodiments dry etching will be preferred due to the anisotropic nature of the etch process.

The sacrificial release layer is then etched with a selective release etchant to remove the sacrificial release layer underneath the functional layer in the area defined by the windows to form the suspended MEMS structure.

FIGS. 1A-1F illustrate aspects of an exemplary embodiment of a method for forming a suspended MEMS structure in accordance with one or more aspects of the present invention.

As shown in FIG. 1A, a process for forming a suspended MEMS begins with growing a thin epitaxial sacrificial release layer 102 and one or more epitaxial Group III-Nitride (III-N) functional device layers 103 on a substrate 101. In many embodiments,

103151-WO1

sacrificial release layer 102 will have a thickness that is much less than the thickness of the functional device layer 103, but such a disparity in thickness is not an essential aspect of the sacrificial release layer in the process of the present invention.

Sacrificial release layer 102 acts as a template for subsequent growth of functional device layer 103. In accordance with the present invention, all of substrate 101, sacrificial release layer 102, and functional device layer 103 are typically formed from single-crystal materials, though as described below, in some cases, one or more of substrate 101 or sacrificial release layer 102 can be formed from other suitable polycrystalline materials, while functional device layer 103 can be formed from suitable polycrystalline or amorphous materials. Suitable amorphous materials for functional device layer 103 can include oxides such as SiO₂, Al₂O₃, TiO₂ etc., with a transition metal nitride sacrificial release layer often being advantageous for use with an amorphous functional device layer.

In many embodiments, sacrificial release layer 102 will be formed from a single-crystal transition metal nitride (TMN) material and functional device layers 103 will be formed from a single-crystal III-N material. In any case, the material used for sacrificial release layer 102 should be chosen to be compatible with the materials used for substrate 101 and functional device layer 103, such that substrate 101, sacrificial release layer 102, and functional device layer 103 have similar crystal structures with 3- or 6-fold symmetry and similar in-plane lattice constants a to allow for the epitaxial growth of the sacrificial release layer 102 on the substrate 101 and for further epitaxial growth of the functional device layers 103 on the sacrificial release layer 102.

For example, if the functional device layers 103 are single-crystal III-N materials, then substrate 101 can be single-crystal hexagonal SiC, having either the 4H or 6H polytype. In addition, the material for sacrificial release layer 102 should be chosen so that it can be more easily removed by selective etching compared to the substrate 101, functional device layer 103, or any additional layers or materials used in the device structure.

In some embodiments, additional layers, such as one or more additional functional layers or one or more buffer layers may optionally be grown on the substrate 101 prior to the sacrificial release layer 102, where in some embodiments they can be configured to be

103151-WO1

included as an active part of the device, while in other embodiments they can be configured to induce higher quality material growth of the sacrificial release layer 102 and functional device layer 103.

Device structures that were experimentally demonstrated by the inventors at the Naval Research Laboratory (NRL) included tantalum nitride (Ta₂N) and niobium nitride (Nb₂N) transition metal nitride (TMN) sacrificial release layers 102 grown by electron beam evaporation molecular beam epitaxy on single-crystal 4H- and 6H-SiC substrates 101. Ta₂N, Nb₂N, and SiC all have hexagonal crystal structures and similar in-plane lattice constants a , where the lattice constant $a_{\text{SiC}} = 3.073 \text{ \AA}$, $a_{\text{Ta}_2\text{N}} = 3.041 \text{ \AA}$, and $a_{\text{Nb}_2\text{N}} = 3.055 \text{ \AA}$, allowing the sacrificial release layer 102 to be grown epitaxially oriented to the SiC substrate 101 in single-crystal form with low defect density.

Ta₂N and Nb₂N have the further advantages that any functional device material layers that can be grown on SiC can also be grown on Ta₂N or Nb₂N with comparable quality due to the similar lattice constants and hexagonal crystal structure of SiC and Ta₂N or Nb₂N. For example, GaN and AlN have wurtzite crystal structures with $a_{\text{GaN}} = 3.189 \text{ \AA}$ and $a_{\text{AlN}} = 3.112 \text{ \AA}$, and are commonly grown on SiC substrates due to their similar crystal structures and in-plane lattice constants.

Additionally, thermodynamic stability is maintained between the Ta₂N or Nb₂N sacrificial release layers 102, substrate 101, and the functional device layer(s) 103 due to the high melting points of Ta₂N and Nb₂N (>2000 °C), which is well above the growth temperature of most commonly-used growth methods such as molecular beam epitaxy (MBE), metal organic chemical vapor deposition, atomic layer epitaxy, sputtering, etc.

While sacrificial release layer 102 can be grown by a variety of known methods, in a preferred embodiment, the sacrificial release layer 102 is grown in situ with the subsequently grown functional device layer 103 to prevent surface contamination or oxidation. For example, if the functional device layer 103 is grown via MBE, in a preferred embodiment, the sacrificial release layer is also grown in the same growth chamber, e.g., by using an electron-beam evaporated transition metal source and nitrogen plasma. Irrespective of the method for growing the sacrificial release layer 102 and/or functional

103151-WO1

device layers 103, substrate 101 should be cleaned and/or pretreated before the next step, using any method such as wet chemical cleaning and outgassing.

As illustrated in FIG. 1B, in a next step of a method for forming a suspended MEMS structure in accordance with the present invention, the suspended area of the device is first defined by a patterned etch mask 104. Etch mask 104 may comprise any suitable process-compatible material, such as a polymer, metal, insulator, or semiconductor and is typically
5 patterned via photolithography.

In a next step, illustrated in FIG. 1C, an etchant 105 is used to form one or more “windows” 106a/106b defining the outline of the suspended MEMS structure. The etching
10 process may be done through any suitable etching technique such as dry plasma, wet chemical, or ion beam etching, though in many embodiments dry etching will be preferred due to the anisotropic nature of the etch process. Multiple etch chemistries may be required depending on the material used for the functional device layers 103 and the sacrificial
15 release layer 102. Both Ta₂N and Nb₂N can be etched using fluorine and chlorine-containing plasma chemistries. Although the etch process does not have to extend to substrate 101 as shown in FIG 1C, functional device layers 103 must be completely etched to at least the sacrificial release layer 102 so that a selective etchant has access to the sacrificial release layer 102. After etching, etch mask 104 can be removed by a compatible wet or dry etch process, as shown in FIG 1D.

Finally, as illustrated in FIG. 1E, sacrificial release layer 102 is etched using a selective release etchant 107 so as to remove the sacrificial release layer 102 from underneath functional device layer 103 to form the suspended device structure 108. In the
20 embodiment illustrated in FIG. 1F, sacrificial release layer 102 is etched so that semiconductor device structure 108 is completely suspended from the substrate 101 or any other functional or buffer layers below. In other embodiments, sacrificial release layer 102
25 is etched only to undercut the functional device layer 103 so as to form one or more devices that are only partially suspended over the substrate. Though any suitable etchant can be used, it should be chosen so that it does not react significantly with any other layer in the device structure other than the sacrificial release layer 102, with a gas phase etchant being
30 preferable to a liquid or plasma-based etchant for the release of MEMS structures.

103151-WO1

For example, in many embodiments, selective release etchant 107 will be XeF₂ gas, since XeF₂ gas is commonly used in selective etching of Si for MEMS processing, has been used to etch both Ta₂N and Nb₂N, and will not damage a wide variety of metals and insulators such as III-N materials and SiC. The XeF₂ etching 107 of the sacrificial release layer 102 can be performed in XeF₂ etching system such as the Xactix XeF₂ release etch system produced by SPTS, where XeF₂ gas can be flowed into a vacuum chamber at a known pressure. The etching may be performed under continuous XeF₂ flow or by alternating the XeF₂ flow and pumping out the etch chamber for a set time and number of cycles (termed pulse mode). An inert gas such as nitrogen (N₂) may be flowed along with the XeF₂ gas. The etch rate of the Ta₂N or Nb₂N sacrificial release layer 102 may be tailored by adjusting the pressure of the XeF₂ gas and the temperature of the substrate. The etching continues until the functional device layers 103 become suspended to form the final MEMS structure 108 shown in FIG. 1F. Further processing of the device may be required after the release step; however, special care is required not to damage the released structures and reduce device yield.

FIGS. 2A-2C illustrate aspects of a device comprising a suspended semiconductor MEMS device structure and further illustrate aspects of the process for forming such a device in accordance with the present invention, where FIG. 2A is a block diagram illustrating aspects of a III-N device structure comprising a plurality of interdigitated metal electrodes suspended over the substrate by selective etching of a Nb₂N sacrificial layer using XeF₂ gas in accordance with the present invention, FIG. 2B is a SEM micrograph of an exemplary embodiment of such a structure produced by the inventors at NRL, and FIG. 2C shows a magnified view of a portion of the structure illustrated in FIG. 2B.

Thus, in the process for forming the device illustrated in FIG. 2A, a sacrificial release layer 202 of Nb₂N is grown on a 6H-SiC substrate 201, with a III-N functional device layer 203 comprising one or more of AlN, GaN, and AlGa_xN grown on top of the Nb₂N layer. In many embodiments, sacrificial release layer 202 will have a thickness much less than the thickness of functional device layer 203. For example, in the exemplary embodiment illustrated in FIG. 2A, Nb₂N sacrificial release layer 202 has a thickness of 100 nm and III-N functional device layer 203 has a thickness of 1000 nm. However, other

103151-WO1

device structures in which the sacrificial release layer and the function device layer have other thicknesses may also be formed and used in the process of the present invention.

Following the formation of sacrificial release layer 202 and functional device layer 203, one or more device components such as interdigitated metal electrodes 209 shown in FIG. 2, can be patterned on III-N functional device layer 203 using any suitable technique such as optical photolithography and metal lift-off. A focused ion beam can then be used to define the outlines of suspended MEMS structure 208 having the metal electrodes 209 on the upper surface thereof, wherein the ion beam defines the outlines of the device by removing the III-N and Nb₂N layers 203 and 202 in selected areas such as “window” area 206. Finally, the sample can be subjected to XeF₂ gas at room temperature to selectively remove Nb₂N sacrificial release layer 202 from substrate 201 and functional device layer 203 and form suspended MEMS device structure 208 (which includes metal electrodes 209) without harming any of the other materials in the structure.

The SEM images shown in FIG. 2B and in the magnified view shown in FIG. 2C illustrate an exemplary embodiment of a structure formed by the process steps described with respect to FIG. 2A. Thus, as shown in FIGS. 2B and 2C, the structure includes a device structure 208 having interdigitated electrodes 209 with the device further including probe pad 210 and being suspended from substrate 201 by means of “window” 206 formed by ion beam etching into functional device layer 203 and sacrificial release layer 202 and the further XeF₂ gas etching of sacrificial release layer 202.

Advantages and New Features

There are several advantages of this invention over old methods.

One advantage is that the TMN sacrificial release layer can be etched by XeF₂ gas. XeF₂ gas etching is a common processing technique used in Si MEMS fabrication. Unlike wet chemical etching, XeF₂ etching avoids reduction in device yield due to stiction or damage to devices from the rinsing and drying process. Additionally, no plasma is required for XeF₂ etching, eliminating possible plasma-induced damage to the active device. XeF₂ is not known to etch either SiC or III-N's and most other metals, insulators, and semiconductors, so the XeF₂ etch release step can easily be implemented into most

103151-WO1

processes. Unlike PEC etching, no extra electrodes or processing steps are required, and there are no limitations on dopants or the bandgap of other layers in the structure.

A second advantage is that the substrate is not used as the sacrificial layer. Due to the close lattice match between the TMN sacrificial release layer and SiC and III-N's, the TMN layer or multiple TMN layers can be grown anywhere in the device stack, allowing for increased device design flexibility. In this case, the substrate is not limited to ones that are easily etched, such as Si or SiC, and any substrate where high quality SiC or III-N material can be grown can be used, including sapphire, AlN, and GaN. Also, by using an epitaxial sacrificial release layer, better control of the undercut depth is possible by controlling the thickness of the sacrificial TMN layer.

Alternatives

There are a number of variations in the above invention.

For example, the sacrificial release layer may be formed from any suitable TMN material such as TaNx, NbNx, WNx, or MoNx or any TMN ternary compound. The sacrificial layer may be deposited by any known growth method, such as sputtering or chemical vapor deposition. While depositing the sacrificial release layer in situ or in vacuo with other device layer(s) may often be preferred, the sacrificial release layer may be deposited ex situ as long as proper cleaning of the substrate, buffer layer(s), and/or functional layer(s) is done prior to growing the sacrificial release layer and proper cleaning of the sacrificial release layer prior is done prior to growing additional functional layer(s) to achieve a native oxide-free surface for further growth.

Also, although the technique used in the method of the present invention is particularly suited for the growth of epitaxial device structures using the III-N material system, which are commonly grown on SiC substrates, the functional device layers are not limited to any particular material system and any suitable material can be used. For example, the substrate and functional device layers are not limited to SiC or III-N materials or even single-crystal materials for epitaxial growth. Any material(s) can be grown on the sacrificial layer as long as the deposited material(s) are in thermodynamic equilibrium with the sacrificial layer at the growth temperature, and a suitable etchant for the sacrificial layer can be found which does not attack the substrate or deposited material(s).

103151-WO1

In addition, there are many optional steps after the functional device layers are grown. Devices may be further processed using common semiconductor device processing techniques such as photolithography, metallization, etching, annealing, ion implantation, etc. Due to the high melting point and thermodynamic stability of the TMN sacrificial layer, a large thermal budget is available for subsequent processing steps. Ideally, the MEMS structure should be released after all device processing steps are completed where the suspended structure could be damaged.

Finally, in addition, although XeF₂ gas was used in the exemplary embodiments described above, other gases and wet chemical etches may also provide adequate selectivity when etching the sacrificial layer. For example, ClF₃ gas has been shown to etch Ta₂N₅, see, e.g., D.E. Ibbotson, J.A. Mucha, D.L. Flamm, and J.M. Cook, "Selective interhalogen etching of tantalum compounds and other semiconductor materials," Applied Physics Letters 46, 794 (1985), while suitable wet etch mixtures may include hydrofluoric acid, nitric acid, and/or hydrochloric acid.

Although particular embodiments, aspects, and features have been described and illustrated, it should be noted that the invention described herein is not limited to only those embodiments, aspects, and features, and it should be readily appreciated that modifications may be made by persons skilled in the art. The present application contemplates any and all modifications within the spirit and scope of the underlying invention described and claimed herein, and all such embodiments are within the scope and spirit of the present disclosure.

103151-WO1

What is claimed is:

1. A method for fabricating a suspended MEMS structure, comprising:
providing a substrate comprising a single-crystal material;
5 epitaxially growing a sacrificial release layer on an upper surface of the substrate, the substrate and the sacrificial release layer having similar crystal structures with 3- or 6-fold symmetry and similar in-plane lattice constants;
epitaxially growing a functional device layer on an upper surface of the sacrificial release layer;
10 patterning a portion of the functional device layer to define an outline of a suspended MEMS structure to be formed from a portion of the functional device layer;
in a first etching step, etching the patterned portion of the functional device layer to form one or more windows in the functional device layer and to further define the outline of the suspended MEMS structure to be formed from the functional device layer; and
15 in a second etching step, using a selective release agent, etching the sacrificial release layer to remove the sacrificial release layer from underneath at least the portion of the functional device layer comprising the suspended MEMS structure.
2. The method according to claim 1, wherein at least one of the sacrificial release layer
20 and the functional device layer comprises a single-crystal material.
3. The method according to claim 1, wherein at least one of the sacrificial release layer and the functional device layer comprises a polycrystalline material.
- 25 4. The method according to claim 1, wherein the functional device layer comprises an amorphous material.

103151-WO1

5. The method according to claim 1, wherein the substrate is one of Si, SiC, sapphire, AlN, and GaN.
6. The method according to claim 1, wherein the sacrificial release layer comprises a single-crystal or poly-crystalline transition metal nitride (TMN) or a ternary TMN compound.
7. The method according to claim 6, wherein the sacrificial release layer comprises one of Nb₂N, Ta₂N, tantalum nitride (TaN_x), niobium nitride (NbN_x), tungsten nitride (WN_x), and molybdenum nitride (MoN_x), where $x > 0$.
8. The method according to claim 1, wherein the functional device layer comprises a single-crystal, polycrystalline, or amorphous Group III-Nitride (III-N) material.
9. The method according to claim 1, wherein the functional device layer comprises SiC.
10. The method according to claim 1, wherein the functional device layer is patterned using photo, imprint, or e-beam lithography.
11. The method according to claim 1, wherein the first etching step is performed by one of dry plasma etching, wet chemical etching, or ion beam etching.
12. The method according to claim 1, wherein the first etching step further etches the selective release layer to extend the window to the substrate.

103151-WO1

13. The method according to claim 1, wherein the selective release agent used in the second etching step is XeF₂ gas.

14. The method according to claim 1, wherein the selective release layer is formed from Ta₂N and the selective release agent is ClF₃ gas.

15. The method according to claim 1, wherein the selective release agent is a wet-chemical etchant.

16. The method according to claim 15, wherein the wet-chemical etchant comprises hydrofluoric acid, nitric acid, and/or hydrochloric acid.

17. The method according to claim 1, wherein the selective release layer is formed *in situ* with formation of the functional device layer.

18. A method for fabricating a suspended MEMS structure, comprising:

providing a substrate;

epitaxially growing a sacrificial release layer on an upper surface of the substrate;

epitaxially growing a functional device layer on an upper surface of the sacrificial release layer, at least one of the substrate, the sacrificial release layer, and the functional device layer comprising a polycrystalline material;

patterning a portion of the functional device layer to define an outline of a suspended MEMS structure to be formed from a portion of the functional device layer;

in a first etching step, etching the patterned portion of the functional device layer to form one or more windows in the functional device layer and to further define the outline of the suspended MEMS structure to be formed from the functional device layer; and

103151-WO1

in a second etching step, using a selective release agent, etching the sacrificial release layer to remove the sacrificial release layer from underneath at least the portion of the functional device layer comprising the suspended MEMS structure.

5 19. A method for fabricating a suspended MEMS structure, comprising:

providing a substrate;

epitaxially growing a sacrificial release layer on an upper surface of the substrate;

epitaxially growing a functional device layer on an upper surface of the sacrificial release layer, at least one of the substrate, the sacrificial release layer, and the functional device layer comprising an amorphous material;

10

patterning a portion of the functional device layer to define an outline of a suspended MEMS structure to be formed from a portion of the functional device layer;

in a first etching step, etching the patterned portion of the functional device layer to form one or more windows in the functional device layer and to further define the outline of the suspended MEMS structure to be formed from the functional device layer; and

15

in a second etching step, using a selective release agent, etching the sacrificial release layer to remove the sacrificial release layer from underneath at least the portion of the functional device layer comprising the suspended MEMS structure.

20

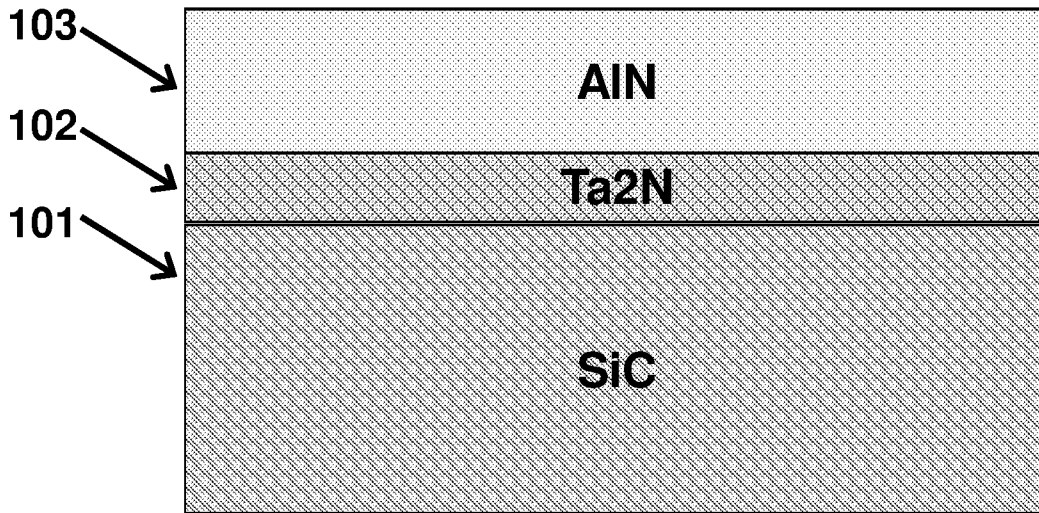


FIG. 1A

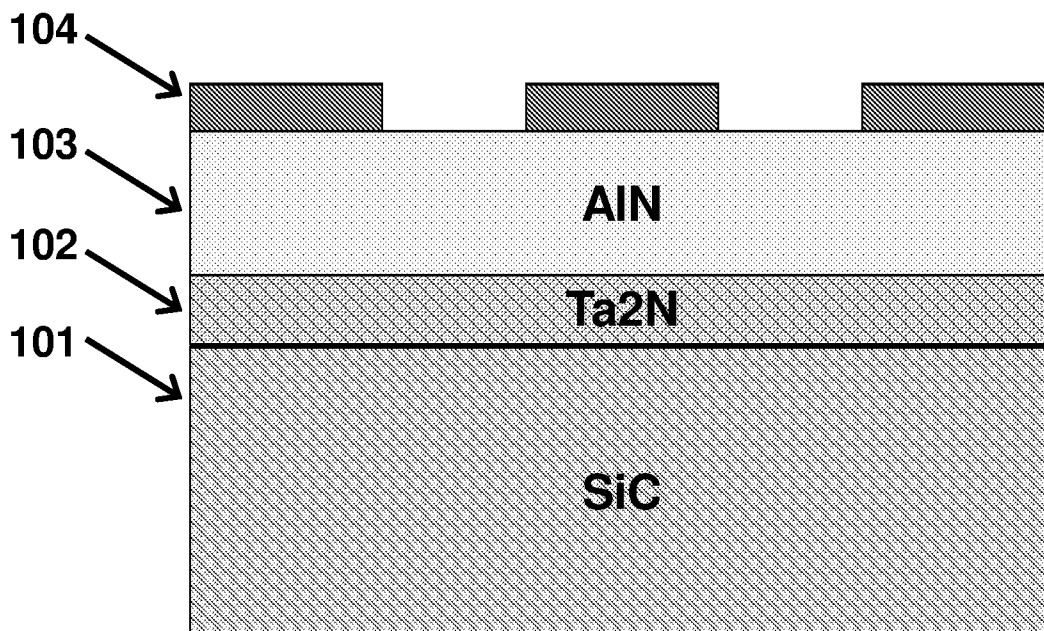


FIG. 1B

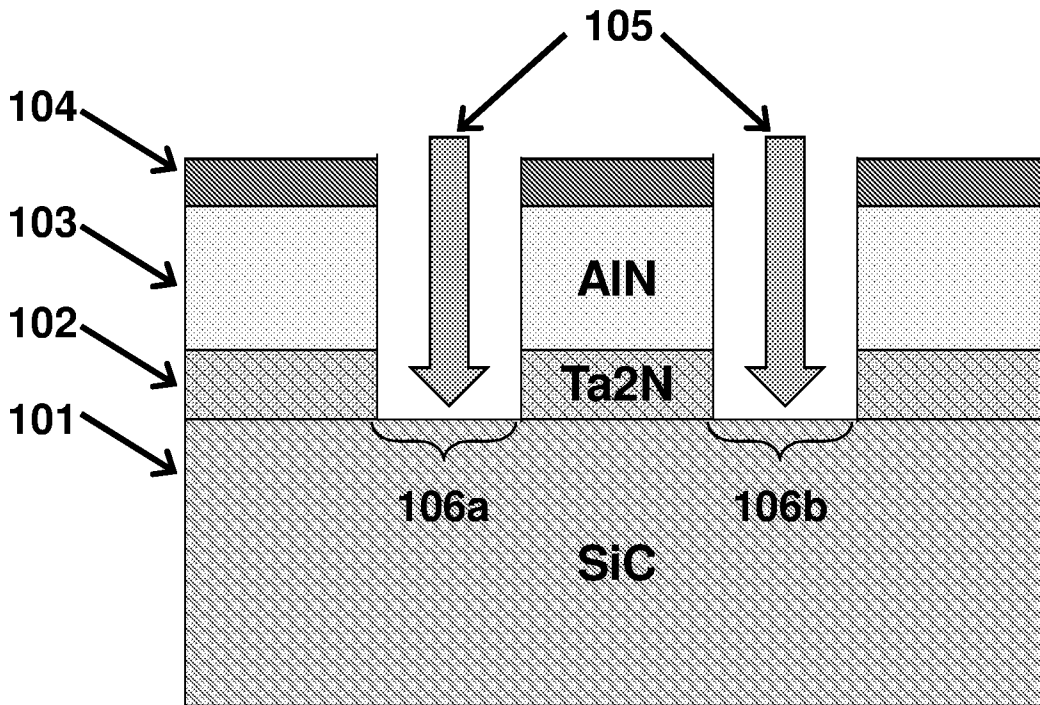


FIG. 1C

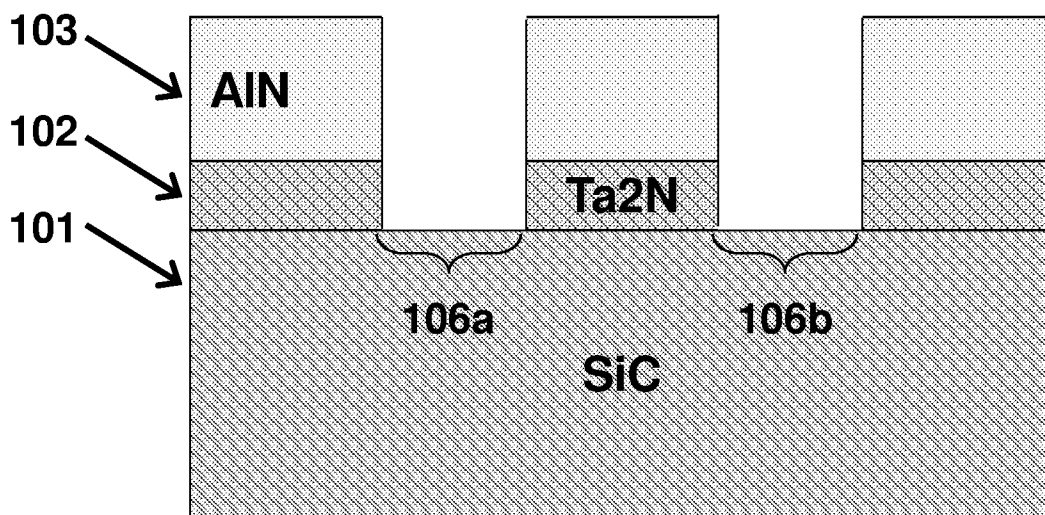


FIG. 1D

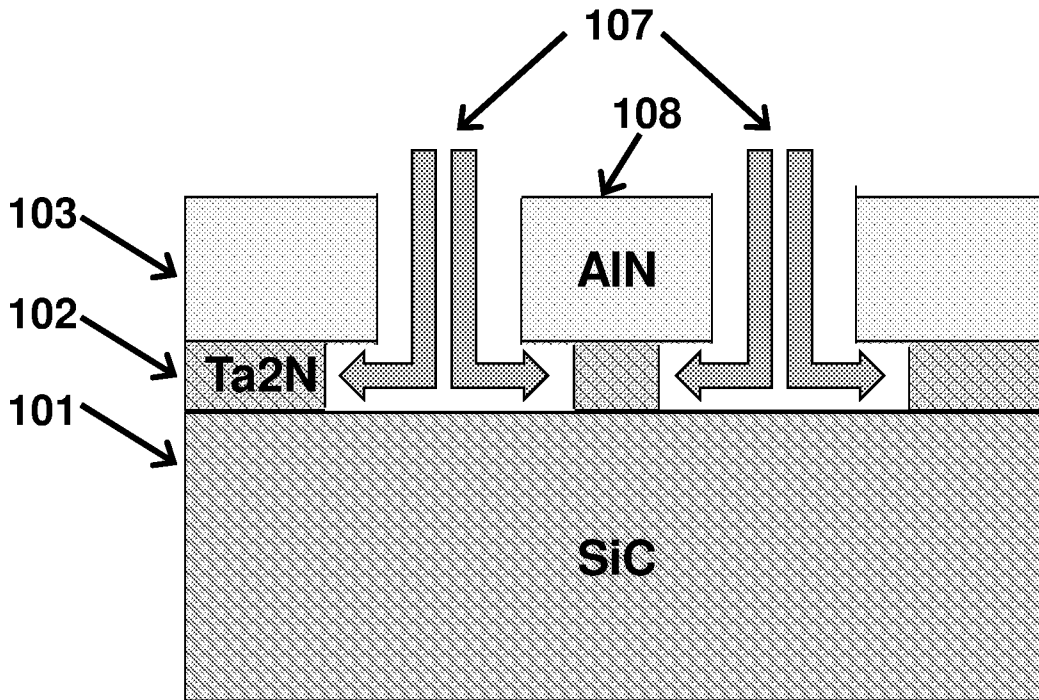


FIG. 1E

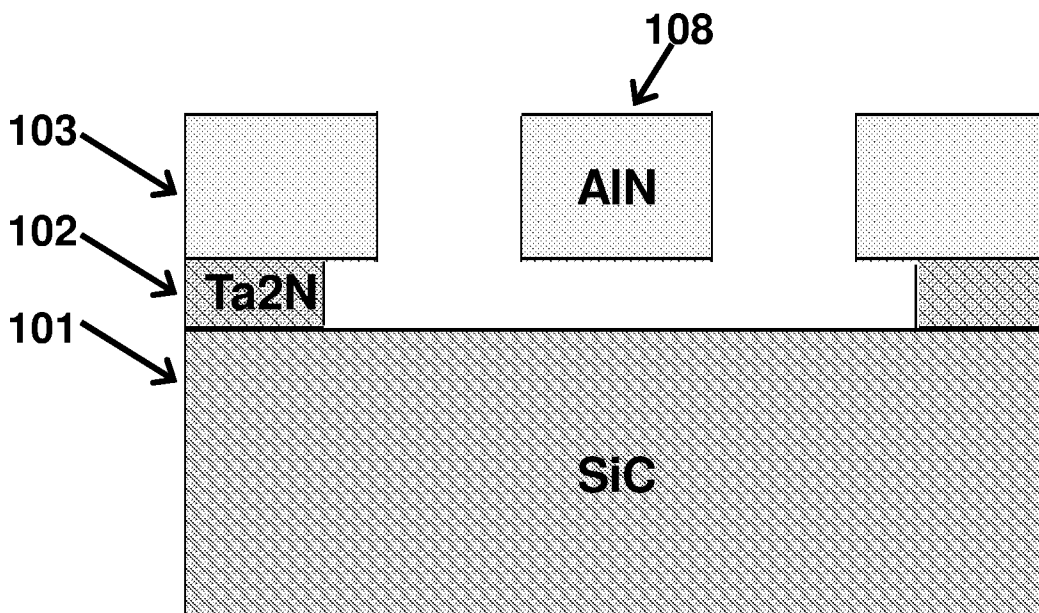


FIG. 1F

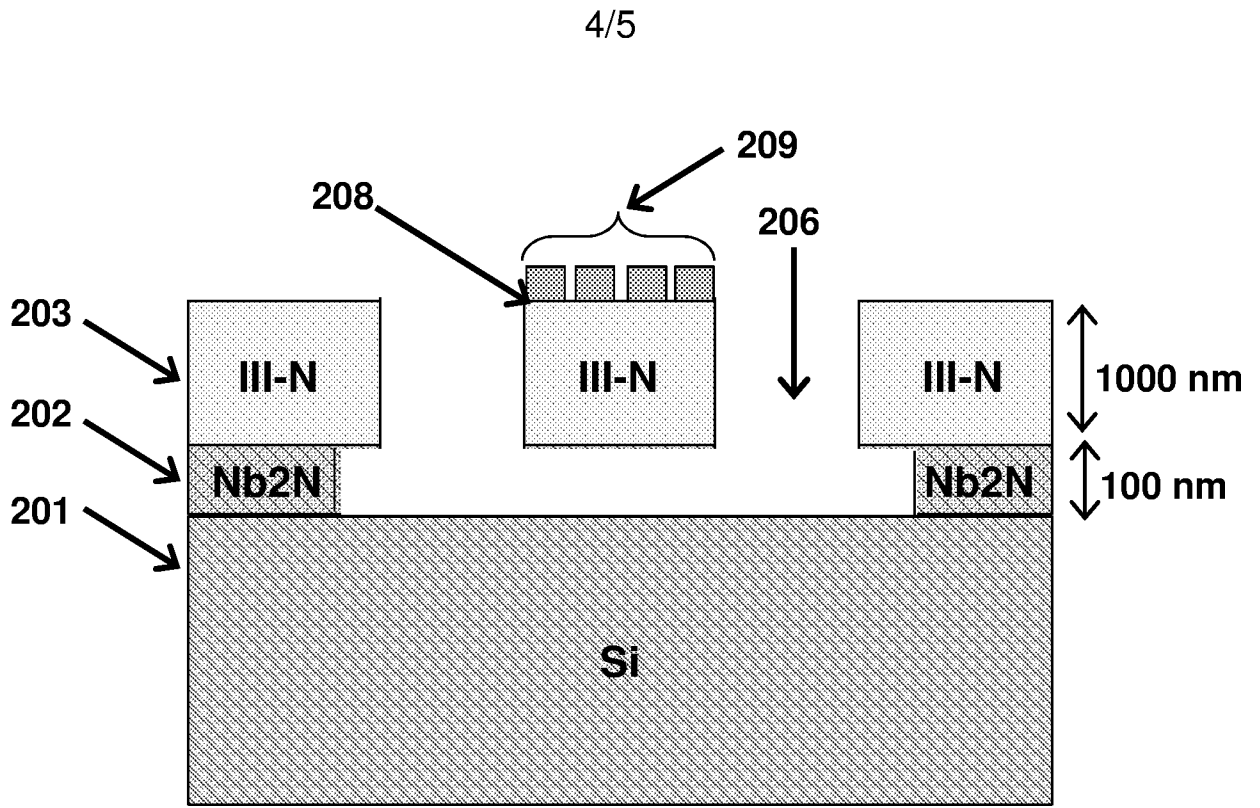


FIG. 2A

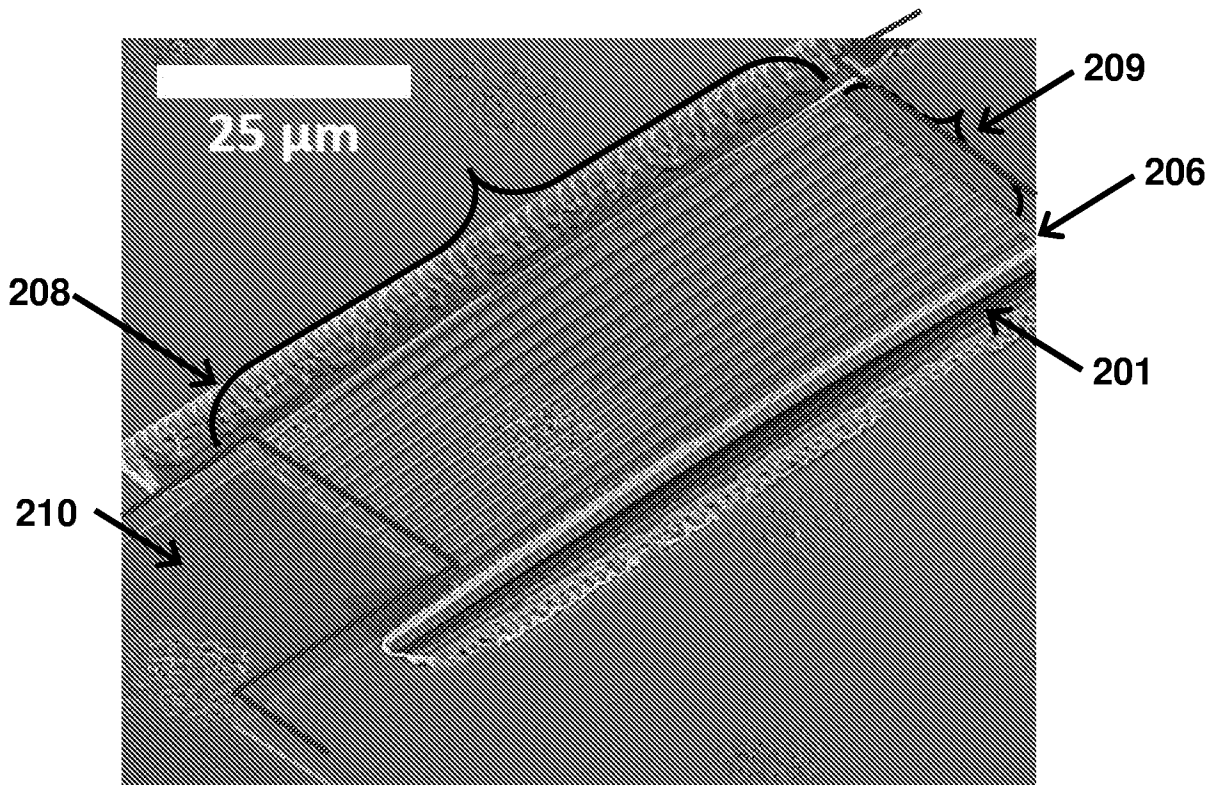


FIG. 2B

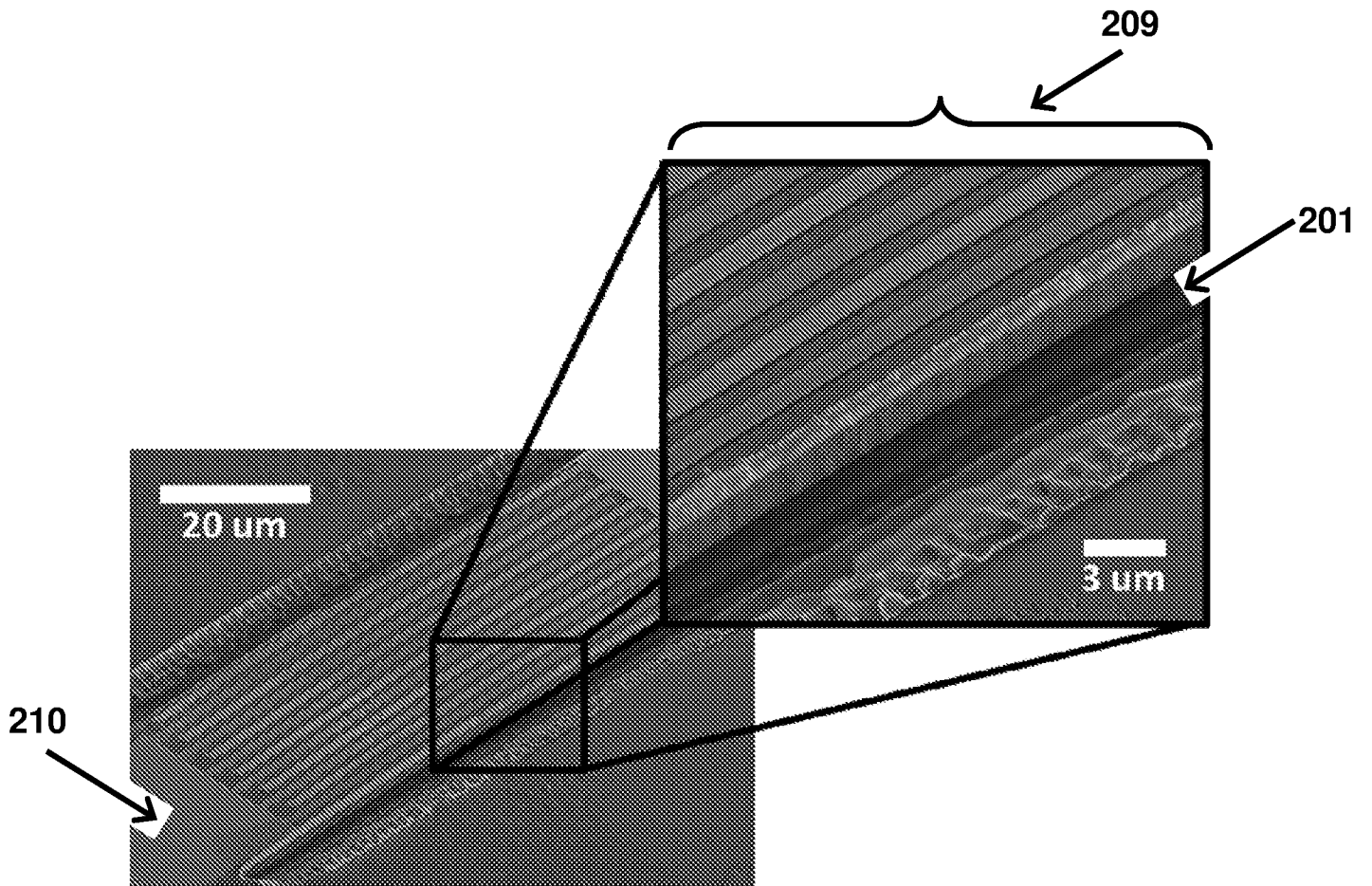


FIG. 2C

INTERNATIONAL SEARCH REPORT

International application No.
PCT/US2016/012133**A. CLASSIFICATION OF SUBJECT MATTER****B81C 1/00(2006.01)i, B81B 7/00(2006.01)i, B81B 7/02(2006.01)i, H01L 27/04(2006.01)i**

According to International Patent Classification (IPC) or to both national classification and IPC

B. FIELDS SEARCHEDMinimum documentation searched (classification system followed by classification symbols)
B81C 1/00; H01L 31/00; H01L 21/76; B81B 7/00; B81B 7/02; H01L 27/04Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched
Korean utility models and applications for utility models
Japanese utility models and applications for utility modelsElectronic data base consulted during the international search (name of data base and, where practicable, search terms used)
eKOMPASS(KIPO internal) & keywords: MEMS, substrate, sacrificial layer, device layer, release layer, single-crystal, etching, and pattern**C. DOCUMENTS CONSIDERED TO BE RELEVANT**

Category*	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	US 2002-0117728 A1 (BROSNIHAN et al.) 29 August 2002 See abstract, paragraphs [0021]-[0022], [0031]-[0036], claims 1, 4, 8, 19-20, and figures 1c, 2f-2h.	1-3,5-18
Y		4,19
Y	EP 1752415 B1 (SEMICONDUCTOR ENERGY LABORATORY CO., LTD.) 27 March 2013 See abstract, paragraph [0027], and figures 2A, 4-5.	4,19
A	WO 2007-078989 A2 (ANALOG DEVICES, INC. et al.) 12 July 2007 See abstract, page 7, line 15 - page 10, line 20, and figures 3A-3E.	1-19
A	WO 2009-144619 A2 (NXP B.V. et al.) 03 December 2009 See abstract, page 4, line 9 - page 5, line 17, and figure 1.	1-19
A	WO 2009-133506 A2 (NXP B.V. et al.) 05 November 2009 See abstract, page 4, line 20 - page 5, line 14, and figures 1-4.	1-19

 Further documents are listed in the continuation of Box C. See patent family annex.

* Special categories of cited documents:

"A" document defining the general state of the art which is not considered to be of particular relevance

"E" earlier application or patent but published on or after the international filing date

"L" document which may throw doubts on priority claim(s) or which is cited to establish the publication date of another citation or other special reason (as specified)

"O" document referring to an oral disclosure, use, exhibition or other means

"P" document published prior to the international filing date but later than the priority date claimed

"T" later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention

"X" document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone

"Y" document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art

"&" document member of the same patent family

Date of the actual completion of the international search

20 April 2016 (20.04.2016)

Date of mailing of the international search report

21 April 2016 (21.04.2016)

Name and mailing address of the ISA/KR

International Application Division
Korean Intellectual Property Office
189 Cheongsa-ro, Seo-gu, Daejeon, 35208, Republic of Korea

Facsimile No. +82-42-481-8578

Authorized officer

RHEE, Jun Ho

Telephone No. +82-42-481-8288



INTERNATIONAL SEARCH REPORT

Information on patent family members

International application No.

PCT/US2016/012133

Patent document cited in search report	Publication date	Patent family member(s)	Publication date
US 2002-0117728 A1	29/08/2002	AU 2002-138101 A	18/02/2002
		US 7083997 B2	01/08/2006
		WO 02-12116 A2	14/02/2002
		WO 02-12116 A3	04/04/2002
EP 1752415 B1	27/03/2013	EP 1752415 A2	14/02/2007
		EP 1752415 A3	30/11/2011
		JP 05127181 B2	23/01/2013
		JP 2007-069341 A	22/03/2007
		US 2007-0037311 A1	15/02/2007
		US 7875483 B2	25/01/2011
WO 2007-078989 A2	12/07/2007	CN 101208990 A	25/06/2008
		CN 101208990 B	14/03/2012
		CN 101351401 A	21/01/2009
		CN 101351401 B	28/11/2012
		CN 101371614 A	18/02/2009
		CN 102572662 A	11/07/2012
		EP 1878306 A2	16/01/2008
		EP 1878306 B1	19/11/2014
		EP 1966077 A2	10/09/2008
		EP 2316786 A2	04/05/2011
		EP 2316786 A3	18/05/2011
		EP 2316787 A2	04/05/2011
		EP 2316787 A3	25/05/2011
		JP 04812139 B2	09/11/2011
		JP 05215871 B2	19/06/2013
		JP 05317231 B2	16/10/2013
		JP 05371133 B2	18/12/2013
		JP 2008-539666 A	13/11/2008
		JP 2009-520449 A	21/05/2009
		JP 2009-524368 A	25/06/2009
		JP 2011-254517 A	15/12/2011
		JP 2013-031228 A	07/02/2013
		JP 2013-176147 A	05/09/2013
		KR 10-1004516 B1	31/12/2010
		US 2006-0237806 A1	26/10/2006
		US 2007-0071268 A1	29/03/2007
		US 2007-0092983 A1	26/04/2007
		US 2007-0165888 A1	19/07/2007
		US 2008-0150104 A1	26/06/2008
		US 2009-0029501 A1	29/01/2009
		US 2010-0285628 A1	11/11/2010
		US 2011-0103622 A1	05/05/2011
		US 2013-065344 A1	14/03/2013
		US 7449356 B2	11/11/2008
US 7825484 B2	02/11/2010		
US 7885423 B2	08/02/2011		
US 8129803 B2	06/03/2012		

INTERNATIONAL SEARCH REPORT

Information on patent family members

International application No.

PCT/US2016/012133

Patent document cited in search report	Publication date	Patent family member(s)	Publication date
		US 8309386 B2	13/11/2012
		US 8422703 B2	16/04/2013
		US 8828773 B2	09/09/2014
		WO 2006-116017 A2	02/11/2006
		WO 2006-116017 A3	08/02/2007
		WO 2007-022249 A2	22/02/2007
		WO 2007-022249 A3	18/05/2007
		WO 2007-078989 A3	11/10/2007
		WO 2007-085017 A1	26/07/2007
WO 2009-144619 A2	03/12/2009	CN 102105389 A	22/06/2011
		EP 2297025 A2	23/03/2011
		US 2011-0198746 A1	18/08/2011
		US 8481365 B2	09/07/2013
		WO 2009-144619 A3	16/09/2010
WO 2009-133506 A2	05/11/2009	WO 2009-133506 A3	20/05/2010